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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Vladimir V. Voronkov et al.

Art Unit 1765

Serial No. 09/972,608

Filed October 5, 2001

Confirmation No. 4591

For METHOD FOR THE PRODUCTION OF LOW DEFECT DENSITY SILICON

Examiner Matthew J. Song

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RESPONSE TO RESTRICTION REQUIREMENT

TO THE COMMISSIONER FOR PATENTS

P.O. Box 1450

Alexandria, VA 22313-1450

SIR:

In response to the restriction requirement dated April 25, 2003, Applicants elect examination of claims 37-43 (Group II).

Applicants therefore withdraw from consideration, without prejudice to their patentability, claims 1-36 (Group I) and claims 44-45 (Group III). Applicants also expressly reserve the right to file one or more divisional applications directed to these claims in the future.

Respectfully submitted,

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